

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : **Hong Hocheng,
Chin Chung Nien** Date : **Aug. 25, 2003**
Serial No. : Group Art Unit :
Filed :
For : **IN-SITU MONITORING METHOD AND SYSTEM FOR
MOLD DEFORMATION IN NANOIMPRINT**


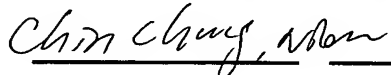
Honorable Commissioner of Patents
and Trademarks
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Attached is a completed Form PTO-1449 and copies of the pertinent parts of the references cited thereon. Comments on any non-English-language references (if any) pursuant to Rule are submitted herewith.

Respectfully submitted

Applicants(s):  _____
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Encl: PTO-1449 & References

FORM PTO-1449 (Substitute)				ATTY. DOCKET NO. ____ <u>03197-UPS</u>		SERIAL NO.	
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Hong Hocheng, Chin Chung Nien			
				FILING DATE			
				GROUP			
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	5,772,905	Jun. 30, 1998	Chou	216	44	Nov. 15, 1995
	AB	6,309,580	Oct. 30, 2001	Chou	264	338	Jun. 30, 1998
	AC						
	AD						
	AE						
FOREIGN PATENT DOCUMENTS							
	AF						
	AG						
	AH						
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
	AO						
EXAMINER				DATE CONSIDERED			
<i>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</i>							